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| SERIAL NUMBER 10/521,248 | FILING OR 371(c) DATE 04/11/2005 RULE | CLASS 438 | GROUP ART UNIT 2891 | ATTORNEY DOCKET NO. 122430 |
| APPLICANTS Hideharu Itatani, Tokyo, JAPAN; Sadayoshi Horii, Tokyo, JAPAN; Masayuki Asai, Tokyo, JAPAN; Atsushi Sano, Tokyo, JAPAN; | | | | |
| ** CONTINUING DATA ***** <i>CME</i> This application is a 371 of PCT/JP03/08964 07/15/2003 | | | | |
| ** FOREIGN APPLICATIONS ***** <i>CME</i> JAPAN 2002-205627 07/15/2002 | | | | |
| IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 12/13/2005 | | | | |
| Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Verified and <i>allowance</i> Acknowledged <i>Examiner's Signature</i> Initials | | STATE OR COUNTRY JAPAN | SHEETS DRAWING 6 | TOTAL CLAIMS 20 |
| | | | | INDEPENDENT CLAIMS 3 |
| ADDRESS 25944 | | | | |
| TITLE Method for manufacturing semiconductor device and substrate processing apparatus | | | | |
| FILING FEE RECEIVED 1030 | FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: | | <input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit | |